

ABSTRACT

The present disclosure provides a carrying apparatus of a semiconductor heat treatment device, and the semiconductor heat treatment device. The carrying apparatus includes a carrying
5 main body. The carrying main body includes a plurality of carrying positions for carrying wafers, and the plurality of carrying positions are arranged at intervals in an axial direction of the carrying main body. The carrying apparatus further includes a temperature measuring apparatus. The temperature measuring apparatus includes a support member and a plurality of
10 temperature measuring assemblies. The support member is connected to the carrying main body, and is located on outer sides of edges of the carrying positions of the carrying main body. The plurality of temperature measuring assemblies are arranged on the support member at intervals in the axial direction of the carrying main body, and each temperature measuring assembly has a temperature measuring end extending to an inner side of the edge of each carrying position and
15 is used for detecting a temperature of a sub-region corresponding to the temperature measuring end. The carrying apparatus of the semiconductor heat treatment device, and the semiconductor heat treatment device provided by the present disclosure may improve the accuracy of temperature measurement on the wafers.

Fig. 2